

David L. Windt

Publications

Peer-Reviewed Journals

1. D. L. Windt and E. M. Gullikson, 'Pd/B₄C/Y multilayer coatings for extreme ultraviolet applications near 10 nm wavelength', *App. Op.*, 54, 5850 – 5860 (2015); doi: 10.1364/AO.54.005850
2. D. L. Windt, 'Laboratory-based x-ray reflectometer for multilayer characterization in the 15-150 keV energy band', *Rev. Sci. Inst.*, 86, 043107 (2015); doi: 10.1063/1.4916737
3. K. Kobayashi, J. Cirtain, A. R. Winebarger, K. Korreck, L. Golub, R. W. Walsh, B. De Pontieu, C. DeForest, A. Title, S. Kuzin, S. Savage, D. Beabout, B. Beabout, W. Podgorski, D. Caldwell, K. McCracken, M. Ordway, H. Begner, R. Gates, S. McKillop, P. Cheimets, S. Platt, N. Mitchell, D. Windt, 'Hi-C: The High Resolution Coronal Imager', *Solar Physics* (2014) doi: 10.1007/s11207-014-0544-4
4. D. Martínez-Galarce, R. Soufli, D. L. Windt, M. Bruner, E. Gullikson, S. Khatri, E. Spiller, J. C. Robinson, S. Baker, E. Prast, 'Multisegmented, multilayer-coated mirrors for the Solar Ultraviolet Imager', *Opt. Eng.* 52, 095102 (2013)
5. J. R. Lemen, A. M. Title, D. J. Akin, P. F. Boerner, C. Chou, J. F. Drake, D. W. Duncan, C. G. Edwards, F. M. Friedlaender, G. F. Heyman, N. E. Hurlburt, N. L. Katz, G. D. Kushner, M. Levay, R. W. Lindgren, D. P. Mathur, E. L. McFeaters, S. Mitchell, R. A. Rehse, C. J. Schrijver, L. A. Springer, R. A. Stern, T. D. Tarbell, J.-P. Wuelser, C. J. Wolfson, C. Yanari, J. A. Bookbinder, P. M. Cheimets, D. Caldwell, E. E. Deluca, R. Gates, L. Golub, S. Park, W. A. Podgorski, R. I. Bush, P. H. Scherrer, M. A. Gummin, P. Smith, G. Auken, P. Jerram, P. Pool, R. Soufli, D. L. Windt, S. Beardsley, M. Clapp, J. Lang, N. Waltham, 'The Atmospheric Imaging Assembly (AIA) on the Solar Dynamics Observatory (SDO)', *Solar Phys.*, 275, 17 – 40 (2012)
6. P. Boerner, C. Edwards, J. Lemen, A. Rausch, C. Schrijver, R. Shine, L. Shing, R. Stern, T. Tarbell, A. Title, C. J. Wolfson, R. Soufli, E. Spiller, E. Gullikson, D. McKenzie, D. Windt, L. Golub, W. Podgorski, P. Testa, M. Weber, 'Initial Calibration of the Atmospheric Imaging Assembly (AIA) on the Solar Dynamics Observatory (SDO)', *Solar Phys.*, 275, 41 – 66 (2012)
7. A. J. Corso, P. Zuppella, D. L. Windt, M. Zangrando, M. G. Pelizzo, 'Extreme ultraviolet multilayer for the FERMI@Elettra free electron laser beam transport system', *Opt. Ex.*, 20, 8006 – 8014 (2012)
8. M. G. Pelizzo, A. J. Corso, P. Zuppella, P. Nicolosi, S. Fineschi, J. Seely, B. Kjørnattawanich, D. L. Windt, 'Long-term stability of Mg/SiC multilayers', *Opt. Eng.* 51, 023801 (2012)
9. M. G. Pelizzo, A. J. Corso, P. Zuppella, D. L. Windt, G. Mattei and P. Nicolosi, 'Stability of EUV multilayer coatings to low energy proton bombardment', *Opt. Ex.* 19, 14838 – 14844 (2011)
10. A. J. Corso, P. Zuppella, P. Nicolosi, D. L. Windt, E. Gullikson, and M. G. Pelizzo, 'Capped Mo/Si multilayers with improved performance at 30.4 nm for future solar missions', *Opt. Ex.*, 19, 13963 – 13973 (2011)
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13. M. G. Pelizzo, M. Suman, D. L. Windt, P. Zuppella and P. Nicolosi, 'EUV multilayer coated mirrors for attophysics, photolithography and space experiments: Software design procedure', *Nucl. Inst. & Meth. A*, 623, 782 – 785 (2010)
14. D. L. Windt and J. A. Bellotti, 'Performance, structure and stability of SiC/Al multilayer films for extreme ultraviolet applications', *App. Op.*, 48, 4932 – 4941 (2009)

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Other Publications

1. D. L. Windt, 'Advancements in hard X-ray multilayers for X-ray astronomy', *Proc. SPIE*, 9603-42 (2015)
2. D. L. Windt and R. Conley, 'Two-dimensional differential deposition: figure correction of thin-shell mirror substrates for X-ray astronomy', *Proc. SPIE*, 9603-47 (2015)
3. H. L. Marshall, N. S. Schulz, D. L. Windt, E. M. Gullikson, E. Blake, D. Getty, Z. McInturff, J. A. Clarke, 'New laterally graded multilayer mirrors for soft X-ray polarimetry', *Proc. SPIE*, 9603-39 (2015)
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